

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Chih-Chien Liu, et al.

Serial No: 09/546,174

Confirmation No.: 4793

Filed: April 11, 2000

For: High Density Plasma Chemical Vapor
Deposition Process

Art Unit: 1711

Examiner: Sergent, Rabon A.

PETITION FOR EXTENSION OF TIME

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the Commissioner for a three-month extension of time extending to December 20, 2007, the period for response to the Office Action dated June 20, 2007. Please charge Deposit Account No. 50-1314 the Extension fee in the amount of \$1,050.00. The responsive papers are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

Dated: December 20, 2007

By: 

William H. Wright
Registration No. 36,312
Attorney for Applicant

1999 Avenue of the Stars, Suite 1400
Los Angeles, California 90067
Telephone: 310-785-4600
Facsimile: 310-785-4601